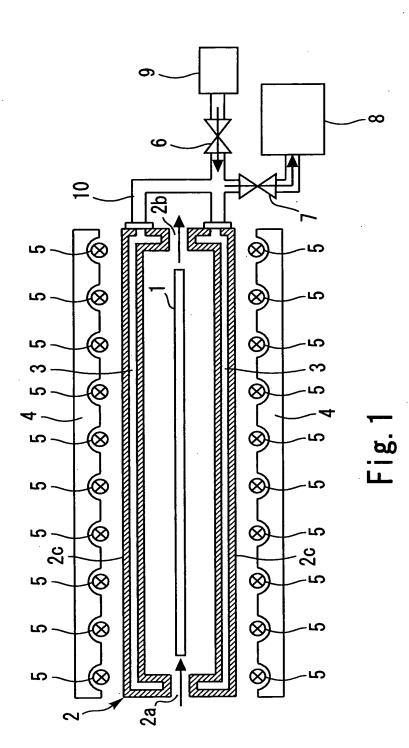
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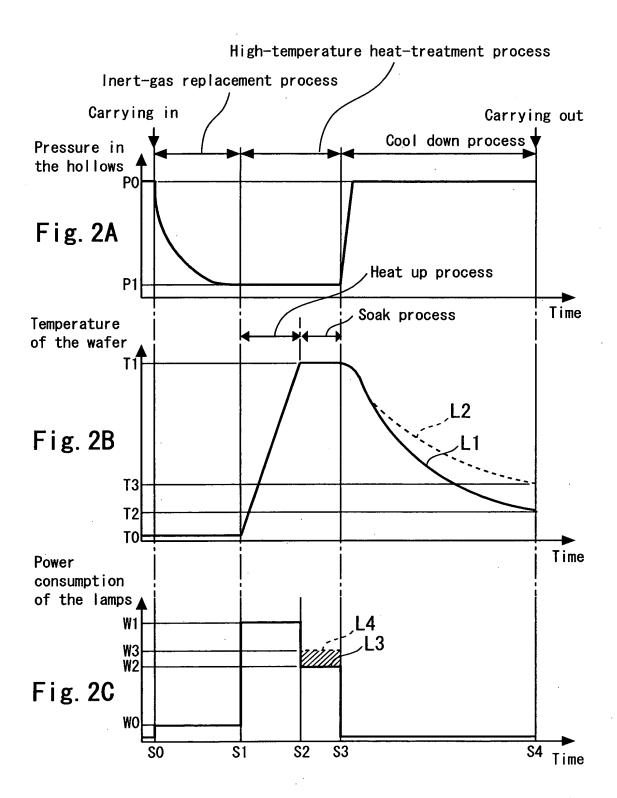
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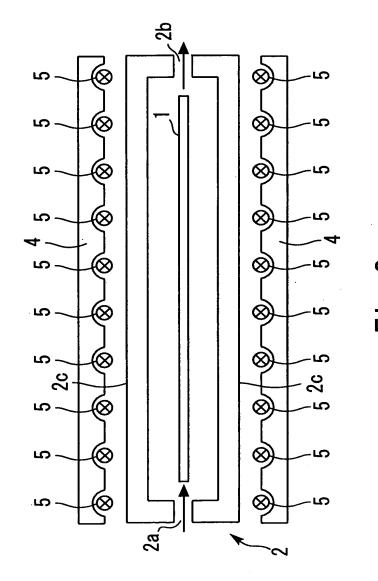
Title: WAFER HEAT-TREATMENT SYSTEM AND WAFER HEAT-TREATMENT METHOD Inventor(s): Yoshimasa KAWASE

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PRIOR ART



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